

H.A.R.E So Negative Tone Photoresist

High Aspect Ratio Epoxy | Superior Quality

HARE SQ™ Negative Epoxy

For MEMS and Microfluidics Applications





H.A.R.E 50 Negative Tone Photoresist

High Aspect Ratio Epoxy | Superior Quality

HARE SQ[™] is a negative epoxy photoresist designed for polymeric MEMS, microfluidics, micromachining, and other microelectronic applications. This resist has excellent chemical, mechanical and thermal resistance, making it suitable for permanent applications. HARE SQ[™] is sensitive to NUV, i-line and broadband wavelengths.

Tone: Negative

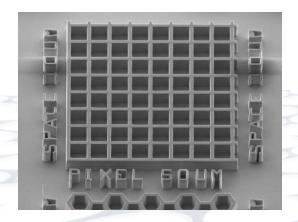
FT: $2 - 100 + \mu m$

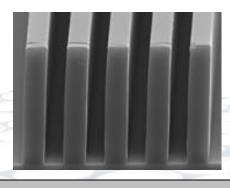
Sensitivity: NUV, broadband, i-line

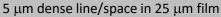
Substrates: Adheres to a variety of substrates; including gold, glass, aluminum, chromium and copper.

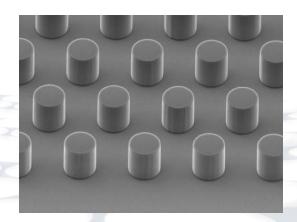
Develop: Designed for use with HARE SQ™ developer. It can be developed using immersion, puddle

or spray puddle.



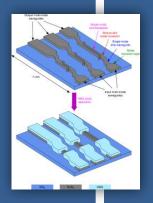






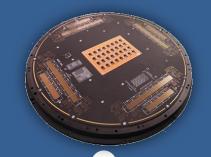






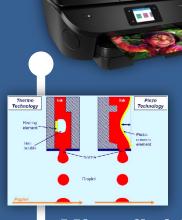


Sensors



MEMS





Microfluidics Inkjet



Antennas

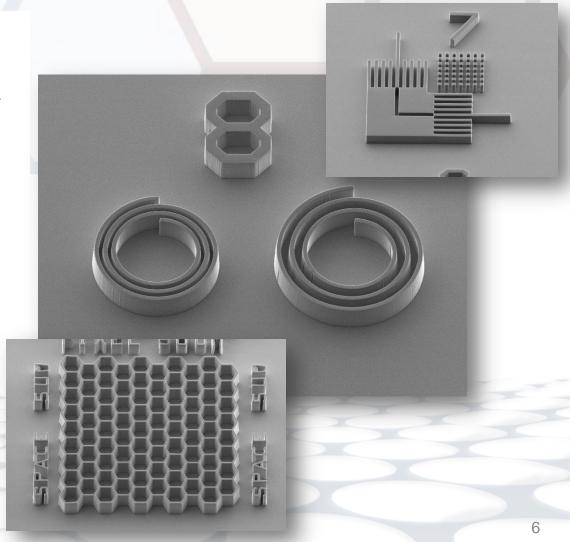
Applications



HARE SQ™ is a negative epoxy resist designed for Microelectronics

Start with better materials, make a better product.

- SUPERIOR
 CLEANLINESS
 AND OPTICAL CLARITY
- ADDED QUALITY TESTING
- BETTER LOT-TO-LOT CONSISTENCY



HARE SQ™ HAS SUPERIOR CLEANLINESS AND OPTICAL CLARITY

KemLab HARE SQ™ resin is cleaner and less yellow.

This leads to fewer particles, more opacity, and fewer micro-bubbles in the final photoresist. Resulting in less variability and better lot-to-lot consistency. **SU-8**

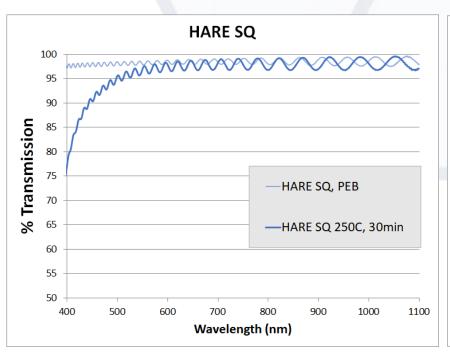


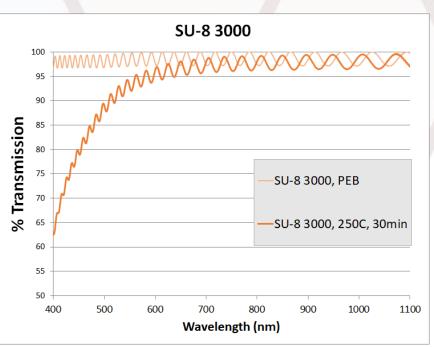






Optical Properties Comparison - 5µm thickness





KemLab HARE SQ has improved transparency versus SU-8



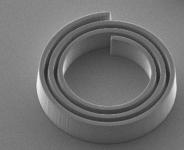
HARE SQ™ HAS ADDED QUALITY TESTING



1. Surface Energy

- Indicates cross-link consistency and crosslink density
- Demonstrates adhesion consistency
- Especially relevant to microfluidic applications where fluids come in contact with the polymeric MEMS structure



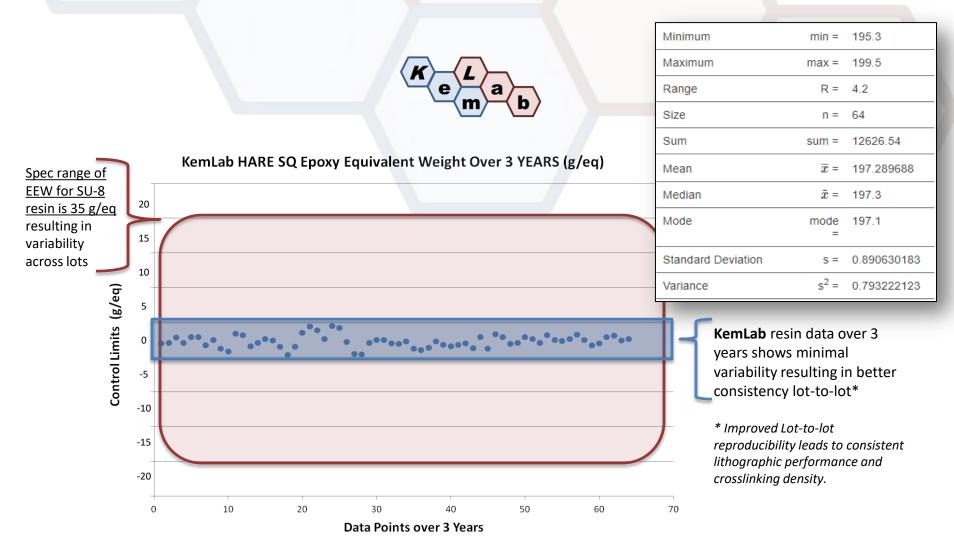




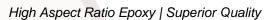
2. Gardner Color

- Demonstrates cleanliness of HARE SQ[™] resist
- Ensures lot-to-lot consistency

3 Years of Resin Lot-to-Lot Data Shows High Consistency and Resin Quality









HARE SQ™ Certificate of Analysis

H.A.R.E. 50 25

Superior Quality High Aspect Ratio Epoxy

Certificate of Analysis

Batch Number	P2-064	Manufacture Date	May-2018
Certified	5/11/2018	Expiration Date	May-2019

Lower

Hnner

<u>Procedure</u>	Unit	<u>Limit</u>	<u>Upper</u> <u>Limit</u>	Pocult
riocedure	Onit	LIIIIL	Limit	<u>Result</u>
Viscosity (25°C) Procedure: QC-002	cst	2350	2550	2446
Film Thickness vs Target Procedure: QC-003	%	-5.0	+5.0	-3%
Surface Energy (crosslinked) Procedure: QC-008	dynes	26	30	27.5
Appearance: Gardner Color Scale Procedure: QC-009	color unit	n/a	3	Pass
Filtration Level	microns	1.0	1.0	1.0

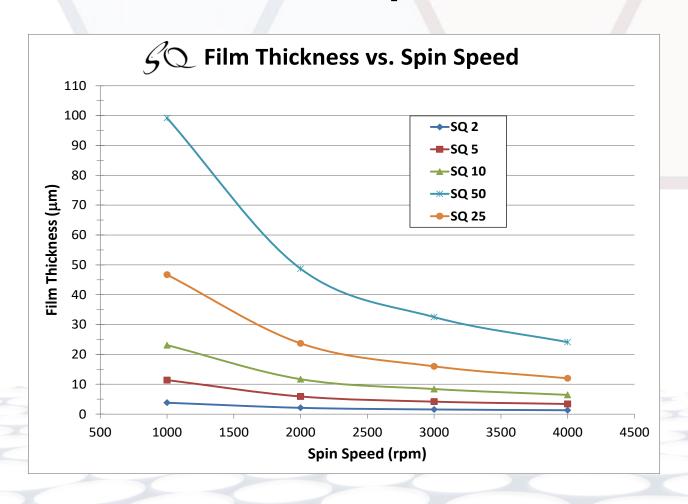






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HARE SQ™ Spin Curve







High Aspect Ratio Epoxy | Superior Quality

HARE SQ™ Properties

Product Details

Property	KemLab HARE SQ™		
Tone	Negative		
Max Single Coat Thickness, μm	100		
Aspect Ratio	10:1		
Storage Condition / Shelf Life	15-30°C / 1 yr		

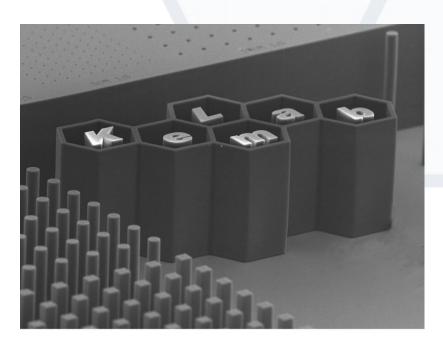
Mechanical Properties

•	
Property	KemLab HARE SQ™
Softening Point / Tg	210°C
Young's Modulus	2.0 GPa
Coeff. of Thermal Expansion, CTE	52 ppm/°C
Tensile Strength	60 MPa
Thermal Conductivity	0.2 - 0.3 W/m-°K
Thermal Stability	315°C

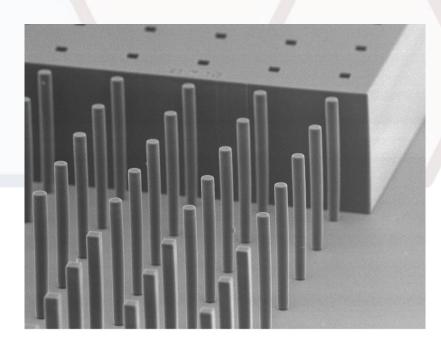
Electrical Properties

Property	KemLab HARE SQ™
Dielectric Constant (relative), 1 GHz, 50% RH	4.0
Dielectric Loss, 1 GHz	~0.02
Dielectric Strength (V/μm)	112
Volume Resistivity (Ω·cm)	~2.5 x 10 ¹⁶

Double Coat Process for Thick Films >100 μm



HARE SQ 50, 70d, 150x, 200 µm FT



HARE SQ 50, 65d, 130x, 200 µm FT

HARE SQ 50 – Double Coat Process for Thick Films

Double Coat Process of HARE SQ 50 for 200 micron film thickness

Coat: 800 rpm, 30 sec, 5 sec spread

Soft Bake: Coat 1: Hotplate 1: 65°C / 5 minutes (put directly on hotplate 2, do not let cool)

Hotplate 2: 95°C / 15 minutes

Coat 2: Hotplate 1: 65°C / 10 minutes (put directly on hotplate 2, do not let cool)

Hotplate 2: 95°C / 30 minutes

Exposure Dose (broadband): 225 mJ/cm² (Use optical cut-off filter at 360 nm for best results)

Post Exposure bake: Hotplate 1: 65°C / 2 minutes (put directly on hotplate 2, do not let cool)

Hotplate 2: 95°C / 15 minutes

Film Relax Time: 60 minutes minimum

<u>Develop</u>: SQ Developer. For best results, use 2 immersion baths

Bath 1: 40 minutes immersion

Bath 2: 10 minute immersion

Rinse: IPA (Isopropyl alcohol). If there is any scum (white precipitate), then immerse in developer again for another 5 -10 minutes

